

We claim:

1. A metrology device couplable to a load port of a semiconductor product tool enclosing a mini-environmental atmosphere and having a load port table for supporting devices to be coupled to the load port, the metrology device comprising:

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a housing preserving an inner atmosphere;

a coupling region for connecting said inner atmosphere to the mini-environmental atmosphere and extending from said housing;

a measuring device for measuring a property of a semiconductor product;

a transport device; and

a support supported by and movable over ground by said transport device, said support supporting said housing and said measuring device, said support dimensioned such that the metrology device being self-supporting in a position appropriate for coupling said coupling region to the load port, the metrology device thereby being couplable to the load port without being supported by the load port table.

2. The metrology device according to claim 1, wherein the metrology device is self-supporting on the ground located at a vertical position deeper than a vertical position of the load port table of the load port.

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3. The metrology device according to claim 1, wherein said coupling region is located at a height appropriate for coupling to the semiconductor product tool.

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4. The metrology device according to claim 3, wherein said coupling region is supported in a vertical position higher than a vertical position of an upper side of the load port table.

5. The metrology device according to claim 1, wherein said support has a recess formed therein for accommodating the load port table.

6. The metrology device according to claim 5, wherein said recess is dimensioned to accommodate the load port table extending horizontally in front of the load port to which the metrology device is coupable to, said recess being allocated at a deeper vertical position than said coupling region.

7. The metrology device according to claim 1, wherein said housing and said coupling region form an upper portion that is

supported in a position preventing contact with contact members, including cinematic coupling pins, of the load port table.

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8. The metrology device according to claim 1, wherein the metrology device is self-supporting in a position appropriate for quick coupling of said coupling region to the load port.

9. The metrology device according to claim 1, wherein said support forms part of said housing preserving said inner atmosphere.

10. The metrology device according to claim 1, wherein said support accommodates said measuring device.

11. The metrology device according to claim 1, wherein said support contains means for adapting a position of the metrology device to different load port sizes.

12. The metrology device according to claim 1, wherein said coupling region has an opening formed therein and a semiconductor product is received through said opening of said coupling region to perform a measurement inside said housing.

13. The metrology device according to claim 1, wherein said transport device is formed of rollers.

14. The metrology device according to claim 1, wherein said support includes a docking region mechanically dockable to the semiconductor product tool.

15. The metrology device according to claim 14, wherein at least one of said coupling region and said docking region contains members for fixing a position of the metrology device relative to the semiconductor product tool.

16. The metrology device according to claim 14, wherein said docking region contains a conduct region coupleable to the semiconductor product tool.

17. The metrology device according to claim 16, wherein said conduct region provides data transfer, power, pressured gas or other media from the semiconductor product tool to the metrology device.

18. The metrology device according to claim 12, wherein said coupling region contains a seal surrounding said opening.

19. The metrology device according to claim 1, wherein at least one of said coupling region and said support contains elements for vibration damping.

20. The metrology device according to claim 1, including a table for vibration damping.
21. The metrology device according to claim 1, wherein the metrology device is a cluster device containing said measuring device for measuring at least two properties of the semiconductor product.
22. The metrology device according to claim 1, wherein the metrology device is a cluster device containing said measuring device for measuring properties of at least two semiconductor products.
23. The metrology device according to claim 1, wherein the semiconductor product tool is at least one of a handling tool and a processing tool.
24. A system, comprising:
a load port for a semiconductor product handling/processing tool, the semiconductor product handling/processing tool enclosing a mini-environmental atmosphere and having a load port table for supporting devices to be coupled to said load port; and

a metrology device couplable to said load port, said metrology device containing:

a housing preserving an inner atmosphere;

a coupling region for connecting said inner atmosphere to the mini-environmental atmosphere and extending from said housing;

a measuring device for measuring a property of a semiconductor product;

a transport device;

a support supported by and movable over ground by said transport device, said support supporting said housing and said measuring device, said support dimensioned such that the metrology device being self-supporting in a position appropriate for coupling said coupling region to said load port, said metrology device thereby being couplable to said load port without being supported by the load port table.